



DISCRETE SiC POWER DEVICES

POWERFUL. PROVEN. PLASMA.

Powerful Proven Plasma

Delivering plasma processing solutions for high volume manufacturing of Silicon carbide (SiC) devices. With solutions for low damage etching of substrates to reduce defect density, controlled feature etch and surface passivation we provide device enabling results at the right Cost of Ownership (CoO). We have developed an innovative set of plasma process solutions designed to enable maximum SiC device performance.

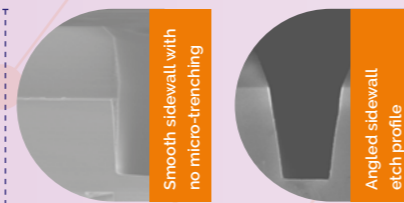
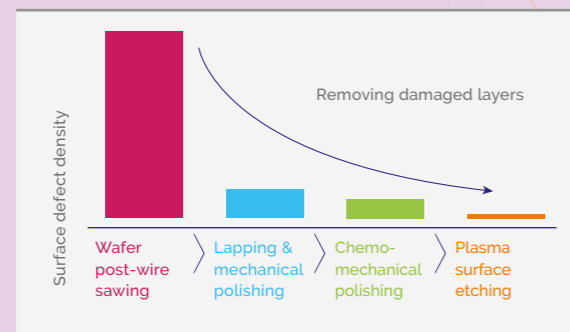


Solutions for your production needs

- Maintain smooth surface
- Removal of sub surface damage layers from sawing and polishing
- Gentle process with no use of abrasive particles
- High-throughput to support current and future capacity demand
- Low cost of ownership (CoO)
- Established in major substrate production suppliers

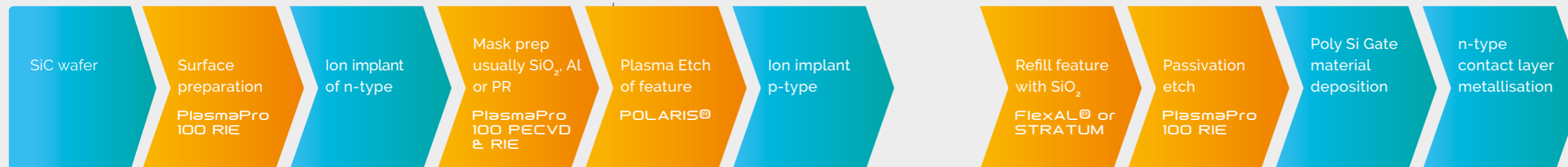
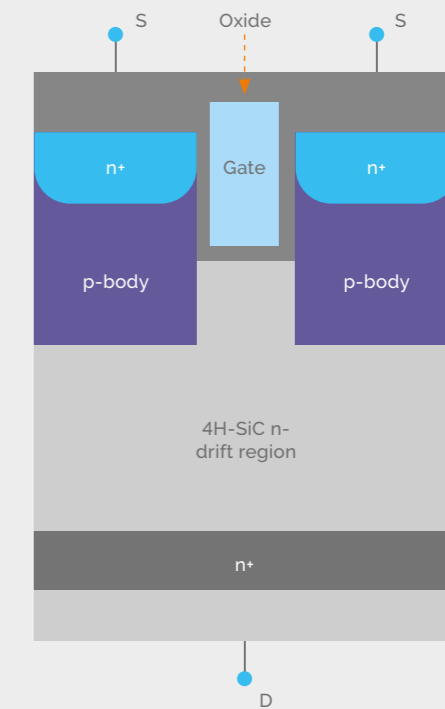
Are you creating the best silicon carbide substrates?

We're supplying leading-edge plasma systems to Tier 1 substrate suppliers for pre-epi surface quality enhancement.



High control of edge profile and surface roughness limits the concentration of electric fields and prevents breakdown.
 Process focus on controlling surface quality to obtain high interface quality with the gate dielectric and minimize leakage.

Simplified device structure



Worldwide Service and Support

Oxford Instruments is committed to supporting our customers' success. We recognise that this requires world class products complemented by world class support. Our global service force is backed by regional offices, offering rapid support wherever you are in the world.

We can provide:

- Flexible service agreements to meet your needs
- Tailored system training courses
- System upgrades and refurbishments
- Immediate access to genuine spare parts and accessories

For further information about our systems, please contact your local Oxford Instruments Plasma Technology office.

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